JC20 Rec'd PCT/PTO 22 JUN 2005

SHIGA7.021APC

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant

Sato, et al.

Int'l Appl. No.

PCT/JP2003/016266

Int'l Filing Date

December 18, 2003

For

POSITIVE RESIST

COMPOSITION AND METHOD OF FORMING RESIST PATTERN

Examiner

Unknown

Group Art Unit

Unknown

PRELIMINARY AMENDMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

Prior to examination on the merits, please amend the present application.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks/Arguments begin on page 7 of this paper.